

Microstructure and conductivity of 8.5YSZ thin films obtained by sol-gel processing

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Motivation



Crystal structure and phases 1000 % 1250 °C



1350 90

SAED: weak additional {112} reflections (see insert in Fig. 5a)

\rightarrow Tetragonal phase (a, = c, = a,) present in all prepared thin films

- Dark-field imaging with {112} intensity:
- Homogeneously distributed tetragonal regions in samples annealed ≤ 1250 °C (Fia. 5b)
- Size of precipitates 0.5-1 nm
- Concentration of precipitates independent of grain boundary/grain core (Fig. 5b) Clustering of tetragonal regions in specimen annealed at 1350 °C (Fig. 5c)

YSZ thin films not completely stabilized in cubic phase, microstructure strongly dependent on the final annealing temperature. [4]

Beference material

Microcrystalline 8.5YSZ SOFC-electrolyte substrates (TOSOH powder) [5] as-sintered + homogenized Annealed (950 °C / 2000 h)



tione c) annealed 8 5YS7

As-sintered substrates:

- Tetragonal phase (a_t = c_t = a_c) clearly identified in 8.5YSZ ^[5] Microstructure similar to thin films annealed ≤ 1250 °C (Fig. 5b, 6a)
- Temporal fluctuation of tetragonal regions (Fig. 6b), suppression by LN₂-cooling
- → No cation-diffusion based process!

Annealed substrates:

Clustering of tetragonal regions (Fig. 6c) + fluctuating regions [5] Slight variations (about ±10 at%) of Y-content observed on nano-scale applying electron energy loss spectroscopy (EELS)

→ Decomposition?

8.5YSZ not stabilized in cubic phase, fluctuating microstructure in as-sintered electrolytes, clustering of tetragonal regions during annealing at 950 °C. [5]

Fig. 8: a) Schematic metastable-stable phase diagram, b) corresponding Gibbs free-energy composition diagram by M. Yashima et al. ^[5]

Phase diagram





"Small" energetic gap between Gibbs free-energy functions of t"-/c-phase in wide range of Y3+-content (Fig. 8)

Formation of metastable t"-phase

- Thin film annealed at 1350 °C + annealed 8.5YSZ substrates:
- Pinning + clustering of tet. regions
- No obvious growth Local variation of Y content on nm-scale
- - Clustered tet. regions t"-phase? Decomposition at higher T, t? (Driving force, mechanism, reason for Pinning)



Fig. 9: DC conductivity of thin films versus mean grain siz

DC conductivity:



· Total resistance governed by grain boundary process (Fig. 9)

10 100 1000 τ¹/s⁻¹ Fig. 9: Distribution of relaxation times

1000

Summarv

YSZ thin films with 8.27 +/- 0.33 mol% Y2O3 prepared by sol-gel process Grain size (5 nm – 1 µm) / degree of porosity adjustable by annealing Residues of the sol-gel process / impurities in the thin films not detectable

Structure

YSZ thin films not completely stabilized in the cubic phase: temporal fluctuations indicative for the existence of the metastable t"-phase Clustering of the observed tetragonal regions at higher temperature and longer time is still not completely understood. First EELS experiments on the nano-scale show slight fluctuations of the Y content.

The presence of the tetragonal phase as well as the resulting microstructure have to be taken into account in modeling the electrical transport properties, since a strong influence of tetragonal nano-scaled regions in 8.5YSZ on ionic conductivity is observed! [5]

Conductivity

Conductivity of microcrystalline YSZ thin films similar to standard electrolyte Reduction of conductivity by decreasing the mean grain size down to nano-scale, total resistance governed by grain boundary process!

Clustered tetragonal regions as reason for degradation of bulk conductivity: Y'₂, and V", -depleted regions as scattering regions for O²⁻ hopping? Pinning of free V., in clustered regions?

References

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Source: LEM

850

6

2. Pyrolysis to burn out the organic fraction of the sol-gel [2]

Experimental techniques

Conventional TEM (CTEM)

using imaging plates

Thin-film quality

850 °C

High-resolution TEM (HRTEM)

techniques (Zeiss Cross-Beam EsB 1540) 200 keV Philips CM200 FEG/ST

Selected-area electron diffraction (SAED)

· Energy-dispersive X-ray spectroscopy (EDXS

3. Additional annealing to adjust the grain size in each single sample

· Investigation of chemical composition / impurities as well as crystal structure

200 keV LEO 922 OMEGA

Scanning TEM (STEM) +

0.8 0.9

Z-contrast imaging

001400 1200 100

high-angle angular dark-field (HAADE) detector:

Temperature [°C]

1000/T [K⁻¹]

→ Series of YSZ thin films with varying mean grain size

and microstructure by transmission electron microscopy (TEM) • TEM sample preparation using standard as well as focussed ion beam (FIB)

- Thin films free of cracks with well-defined thickness/mean grain size (Fig. 1a) [3,4] Narrow-distributed grain size d (5 nm at 650 °C to ~ 1 µm at 1400 °C) Good adhesion on substrates
- Porosity in thin films annealed below 1250 ℃ (Fig. 1b)

Size of pores = mean grain size

Energy [keV]

Grain growth in nano-crystalline films (annealed below 1250 °C) limited by the presence of pores as indicated by the dashed lines in Fig. 2. [4]

Stoichiometry and purity

Fig. 3: EDX spectra of thin films no

 Final Y3+ dopant concentration independent on the 850 °C annealing temperature (Fig. 3) Quantification with respect to a TOSOH 8.5YSZ thick-film electrolyte: 8.27 +/- 0.33 mol% Y203 [4]

- 1600 °C - 1350 °C - 1000 °C 650 90 5 nm 10 2

No Si-/Al-rich glassy phases at the grain boundaries (HRTEM imaging + analytic methods)